



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re A	Application of:)
Inventor: Akira HAMAGUCHI et al.) Group Art Unit: 2623
Applic	eation No.: 10/687,828) Examiner: Not Assigned
Filed:	October 20, 2003)
For:	METHOD AND APPARATUS FOR DETERMINING DEFECT DETECTION SENSITIVITY DATA, CONTROL METHOD OF DEFECT DETECTION APPARATUS, AND METHOD AND APPARATUS FOR DETECTING DEFECT OF SEMICONDUCTOR DEVICES))

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

PRELIMINARY AMENDMENT

Prior to examination, please amend the above-identified application as follows:

Amendments to the Specification are included in this paper.

Amendments to the Claims are reflected in the listing of claims in this paper.

Amendments to the Drawings are included in the attached replacement drawing sheet. The amendments are discussed in this paper and are also illustrated in the attached annotated drawing sheet.

Remarks follow the amendment section of this paper.